

Part II. Detailed Course Information

Course Objectives	
<i>Explain the aims of the course. Maximum 100 words.</i>	
1)	To introduce the concept of scaling and MEMS
2)	To introduce materials used in MEMS
3)	To explain the surface micromachining and bulk micromachining methods used for fabrication of MEMS
4)	To introduce capacitive, piezoelectric, thermal, and IR based sensing and actuating methods
5)	To mention packaging of MEMS

Learning Outcomes	
<i>Explain the learning outcomes of the course. Maximum 10 items.</i>	
1)	Comprehend concept of scaling
2)	Have an understanding of microfabrication methods
3)	Have an understanding of various ways of transduction

Textbook(s)				
<i>List the textbook(s), if any, and other related main course materials.</i>				
Author(s)	Title	Publisher	Publication Year	ISBN
Nadim Maluf	An Introduction to Microelectromechanical Systems Engineering	Artech House, Inc.	1999	0131274988

Reference Books				
<i>List the reference books as supplementary materials, if any.</i>				
Author(s)	Title	Publisher	Publication Year	ISBN
Sergey Edward Lyshevski	Nano- and Microelectromechanical Systems: Fundamentals of Nano- and Microengineering	CRC Press	2000	
M. Elwenspoek, R. Wiegerink	Mechanical Microsensors	Springer-Verlag	2001	
G. T. A. Kovacs	Micromachined Transducers Sourcebook	McGraw-Hill	1998	

Teaching Policy	
<i>Explain how you will organize the course (lectures, laboratories, tutorials, studio work, seminars, etc.)</i>	
There are 3 hours of lectures each week.	

Laboratory/Studio Work	
<i>Give the number of laboratory/studio hours required per week, if any, to do supervised laboratory/studio work, and list the names of the laboratories/studios in which these sessions will be conducted.</i>	
There is no regular laboratory work for this course.	

Computer Usage	
<i>Briefly describe the computer usage and the hardware/software requirements in the course.</i>	

Students are expected to prepare their projects using computer. ANSYS Multiphysics and COMSOL Multiphysics are used for the project.

Course Outline

List the topics covered within each week.

Week	Topic(s)
1	Overview of Microsystems, potential of microsystems
2	Working principles of currently available microsensors, actuators
3	Scaling laws
4	Materials used for common microcomponents and devices
5	Design tools
6	Surface micromachining processes
7	Surface micromachining processes
8	Bulk micromachining processes
9	Transducers; sensing and actuating
10	Capacitive ways of transduction
11	Piezoelectric ways of transduction
12	Thermal transduction
13	IR based sensors
14	Packaging methods

Grading Policy

List the assessment tools and their percentages that may give an idea about their relative importance to the end-of-semester grade.

Assessment Tool	Quantity	Percentage	Assessment Tool	Quantity	Percentage	Assessment Tool	Quantity	Percentage
Homework	5	15	Case Study			Attendance		
Quiz	5	15	Lab Work			Field Study		
Midterm Exam	1	20	Class Participation			Project	1	20
Term Paper			Oral Presentation			Final Exam	1	30

ECTS Workload

List all the activities considered under the ECTS.

Activity	Quantity	Duration (hours)	Total Workload (hours)
Attending Lectures (<i>weekly basis</i>)	14	3	42
Attending Labs/Recitations (<i>weekly basis</i>)	-	-	-
Preparation beforehand and finalizing of notes (<i>weekly basis</i>)	14	0.5	7
Collection and selection of relevant material (<i>once</i>)	1	2	2
Self study of relevant material (<i>weekly basis</i>)	14	1	14
Homework assignments	5	4	20
Preparation for Quizzes	5	1	5
Preparation for Midterm Exams (<i>including the duration of the exams</i>)	1	8	8
Preparation of Term Paper/Case Study Report (<i>including oral presentation</i>)	-	-	-
Preparation of Term Project/Field Study Report (<i>including oral presentation</i>)	1	14	14
Preparation for Final Exam (<i>including the duration of the exam</i>)	1	10	10

TOTAL WORKLOAD / 25	122/25=4.88
ECTS Credit	5

Total Workloads are calculated automatically by formulas. To update all the formulas in the document first press CTRL+A and then press F9.

Justification for the proposal*Maximum 80 words*

As a contemporary subject, the area of microelectromechanical systems (MEMS) is rapidly growing. Therefore, this course is designed to introduce the students basic fabrication methods of microsystems and MEMS based transducers.

Part IV Approval

Proposed by	Faculty Member <i>Give the Academic Title first.</i>	Signature	Date
	Asst. Prof. Dr. Ender Yıldırım		
	Prof. Dr. Taner Altunok		

Departmental Board Meeting Date		Meeting Number		Decision Number	
Department Chair	Prof. Dr. Can ÇOĞUN	Signature		Date	

Faculty Academic Board Meeting Date		Meeting Number		Decision Number	
Dean	Prof. Dr. Celal Zaim ÇİL	Signature		Date	

Senate Meeting Date		Meeting Number		Decision Number	
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